

Notice of References Cited	Application/Control No. 10/040,453		Applicant(s)/Patent Under Reexamination MIYOSHI ET AL.	
	Examiner SCOTT L. JARRETT		Art Unit 3623	Page 1 of 3

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	V	Vollmann, Thomas E. et al., The Facility Layout Problem in Perspective Management Science, Vol. 12, No. 10, June 1966, Pages B450-B-468
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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